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Recent Advances in Thin Film Transistors

Guest Editor:

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Message from the Guest Editor

Dear Colleagues,

The thin film transistor is a hot research topic in the field of displays. It has very important research significance and extensive market application prospects. At present, the key technical problems are mainly that the mobility is not high enough, the reliability is not good enough, the preparation temperature is not low enough, and the manufacturing cost is not low enough. These technical problems have seriously hindered the extensive use of the industry. At present, it is necessary to develop new thin film transistor technology and improve the performance of thin film transistors for the application of thin film transistors in new displays. Original research papers and review articles are invited for this Special Issue.

Dr. Dedong Han

Guest Editor



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Special Issue



Editor-in-Chief

Message from the Editor-in-Chief

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